

Fully Automated Wide Temperature Range Semiconductor Characterization

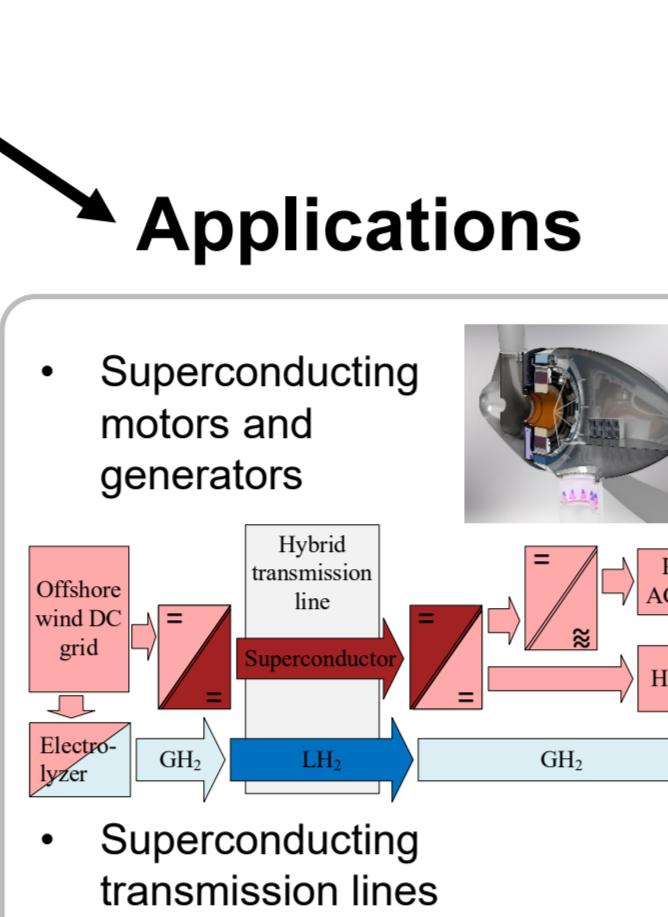
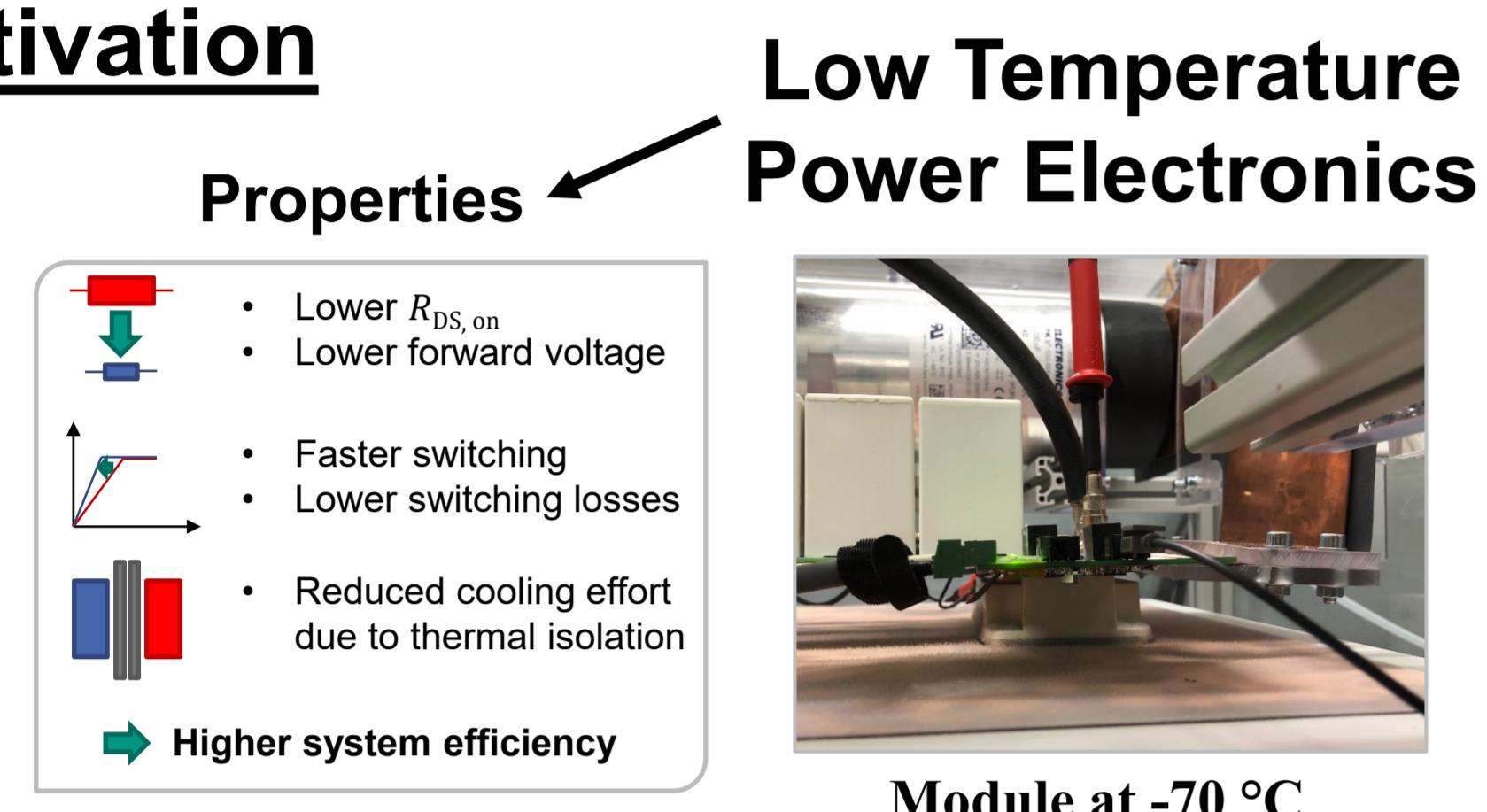
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Motivation

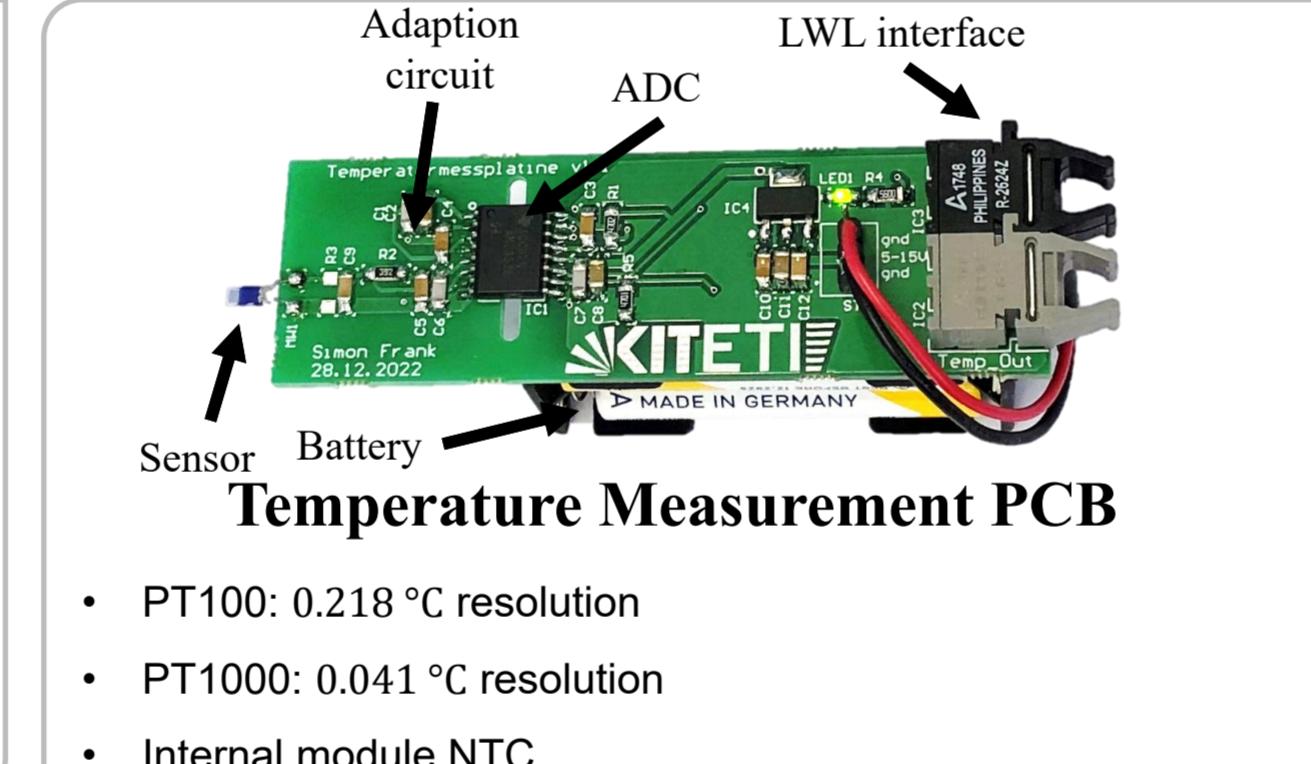
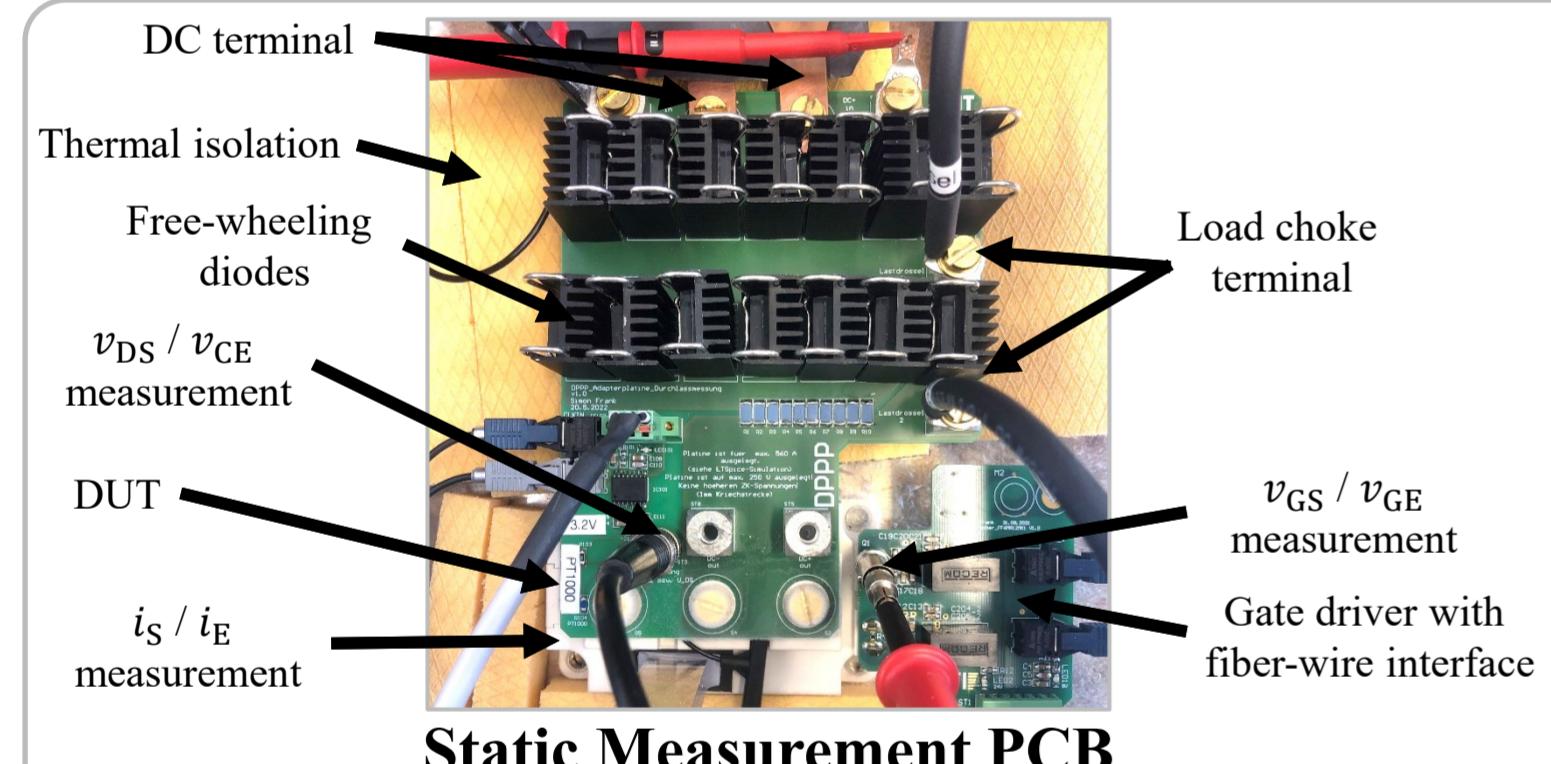
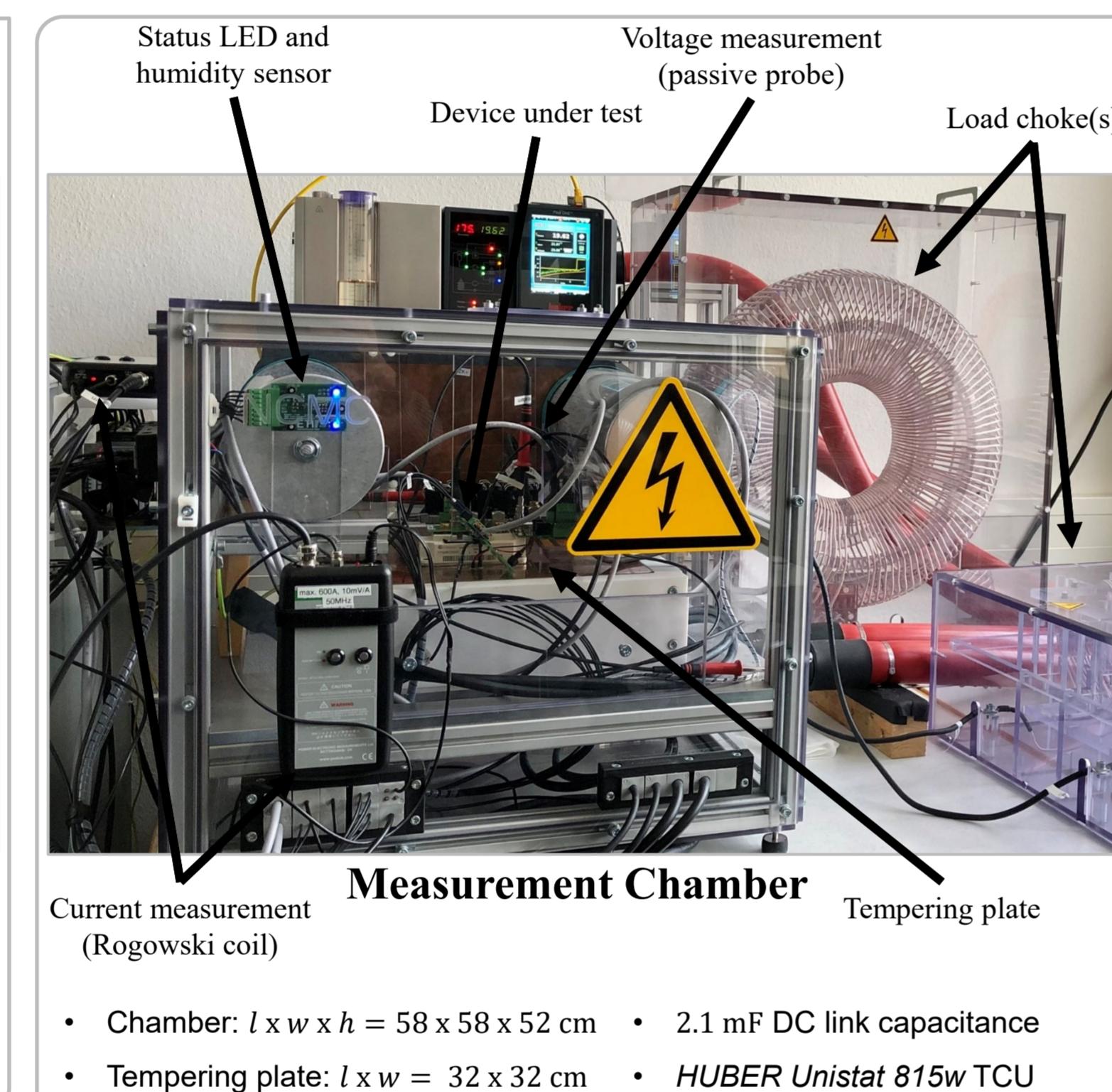
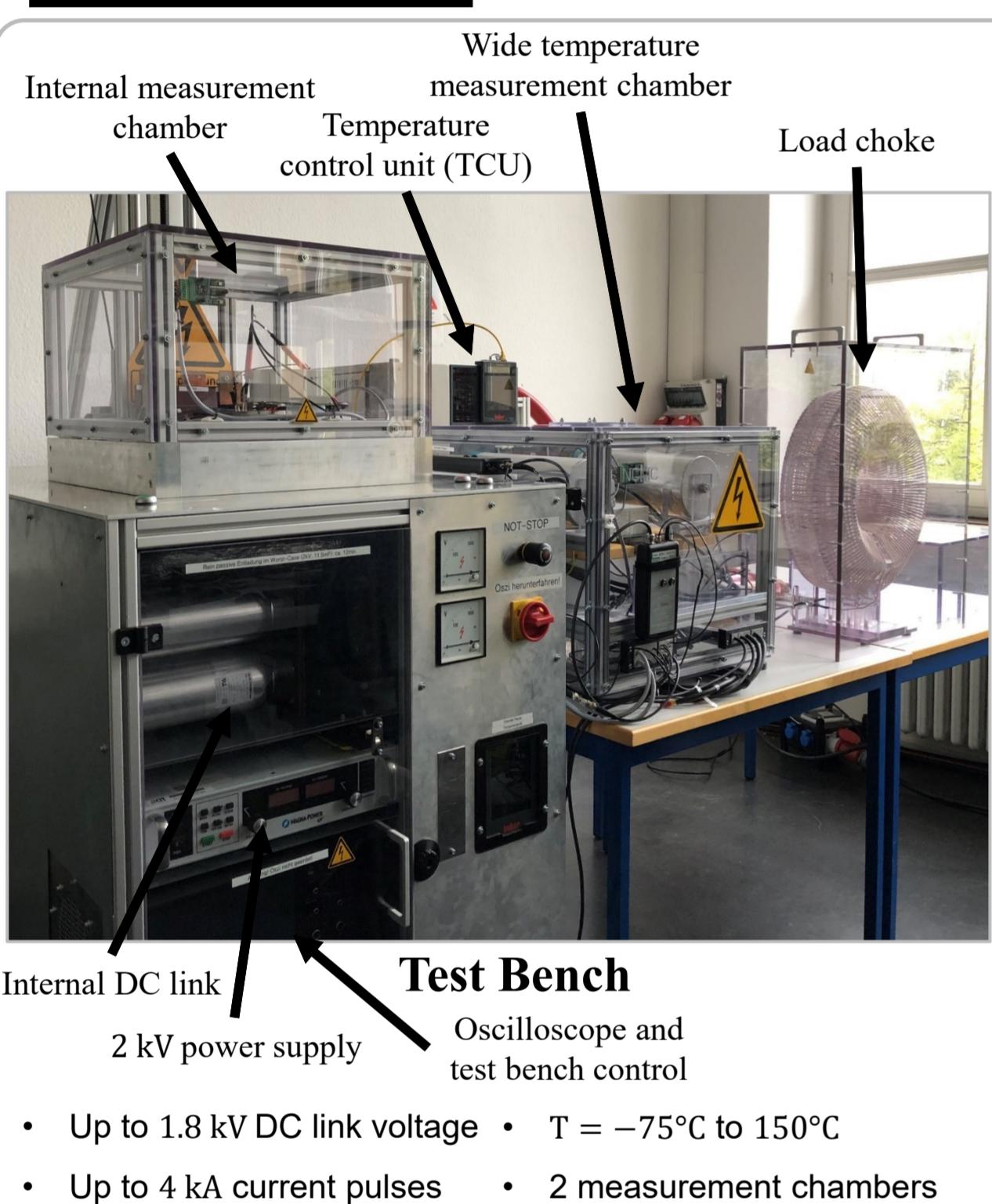


Wide Temperature Range Semiconductor Characterization

- Precise temperature control
- Ensure save temperature operating area of periphery
- Whole module measurement
- Prevent icing
- Easy and flexible configuration, measurement, data evaluation
- Affordable measurement technology

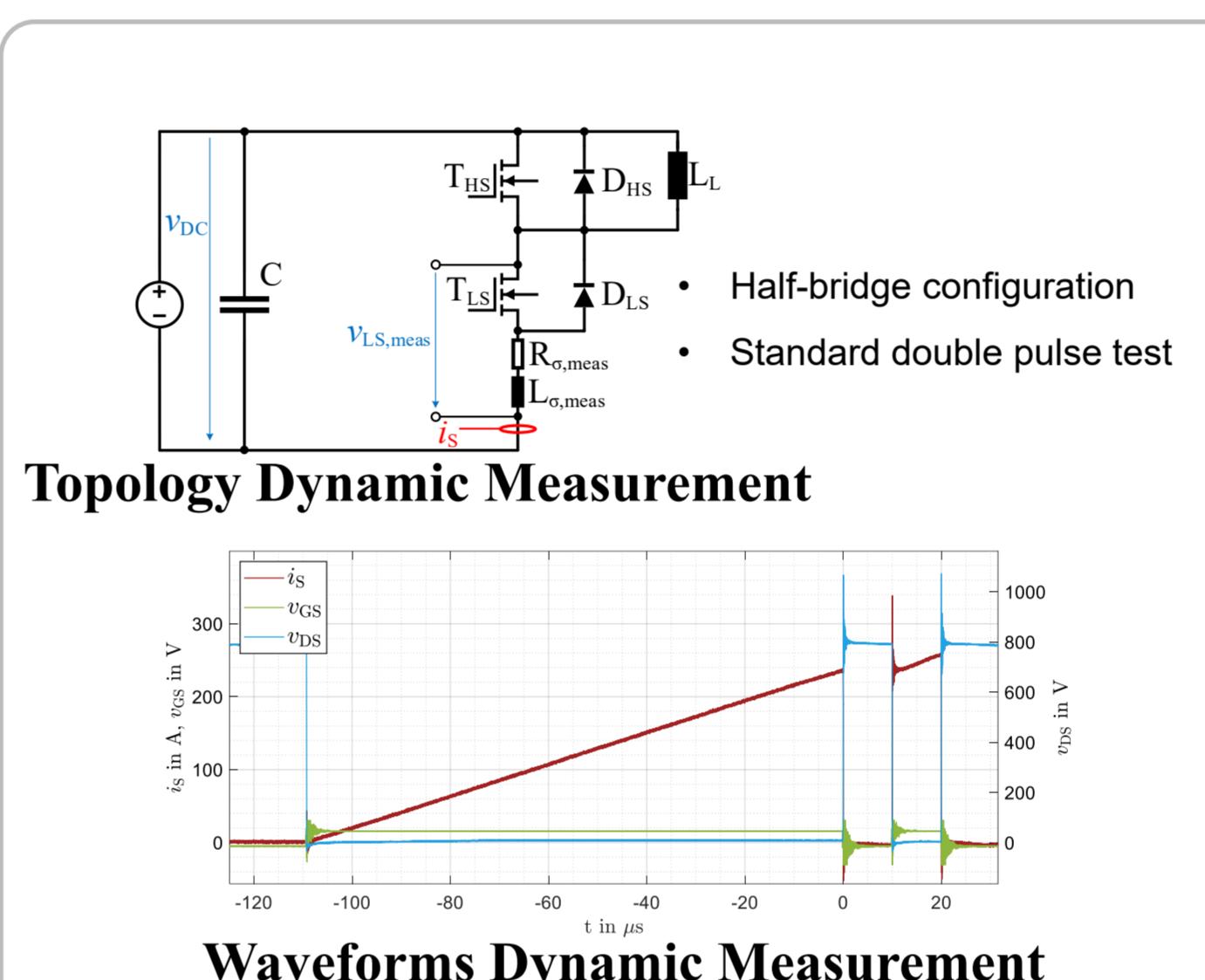
- Temperature control unit
- Tempering plate instead of climatic chamber
- Hermetic, nitrogen filled measurement chamber
- In-house developed control and evaluation software
- Minimized setup (no helium chillers, curve tracers...)

Semiconductor Test Bench

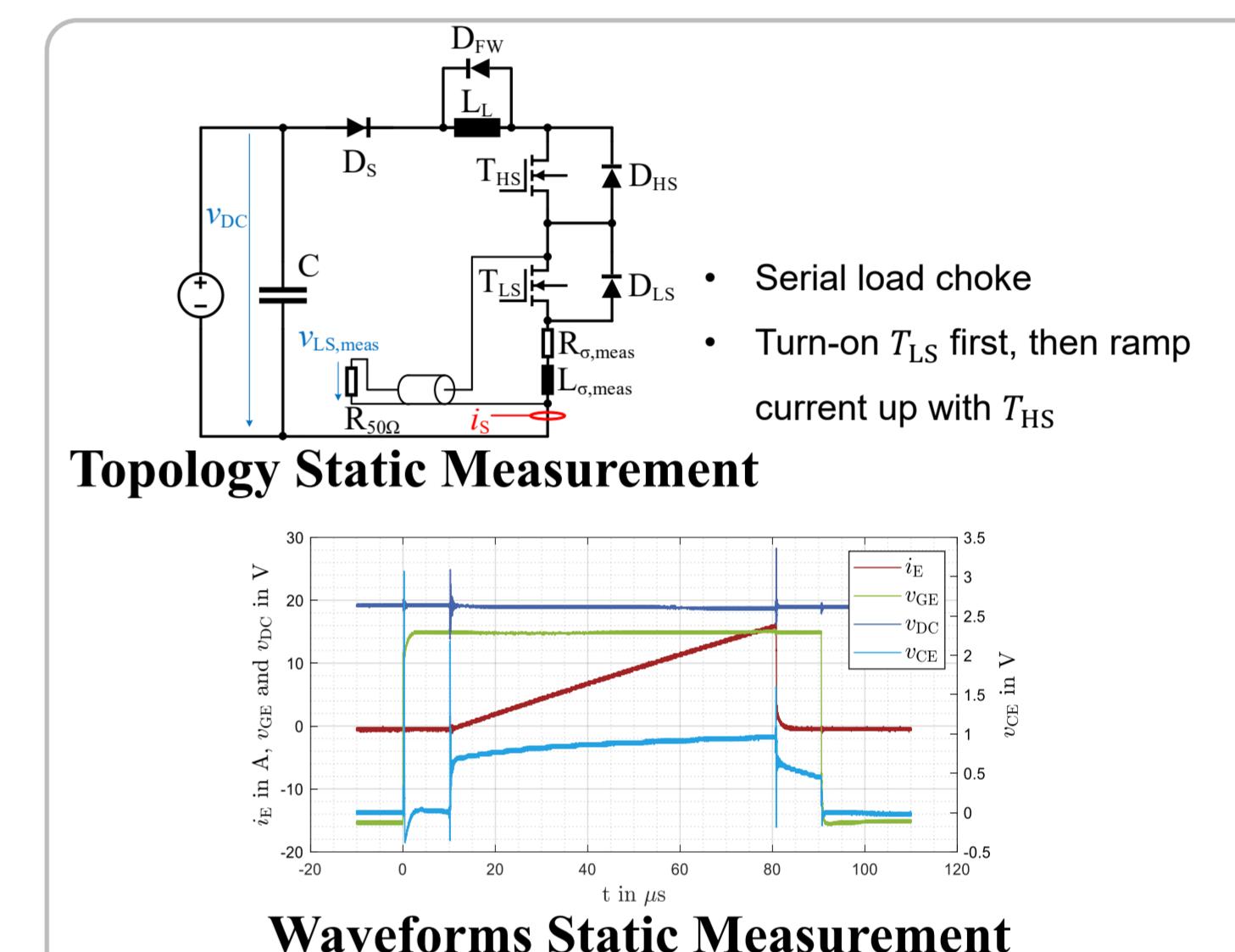


Hardware Setup

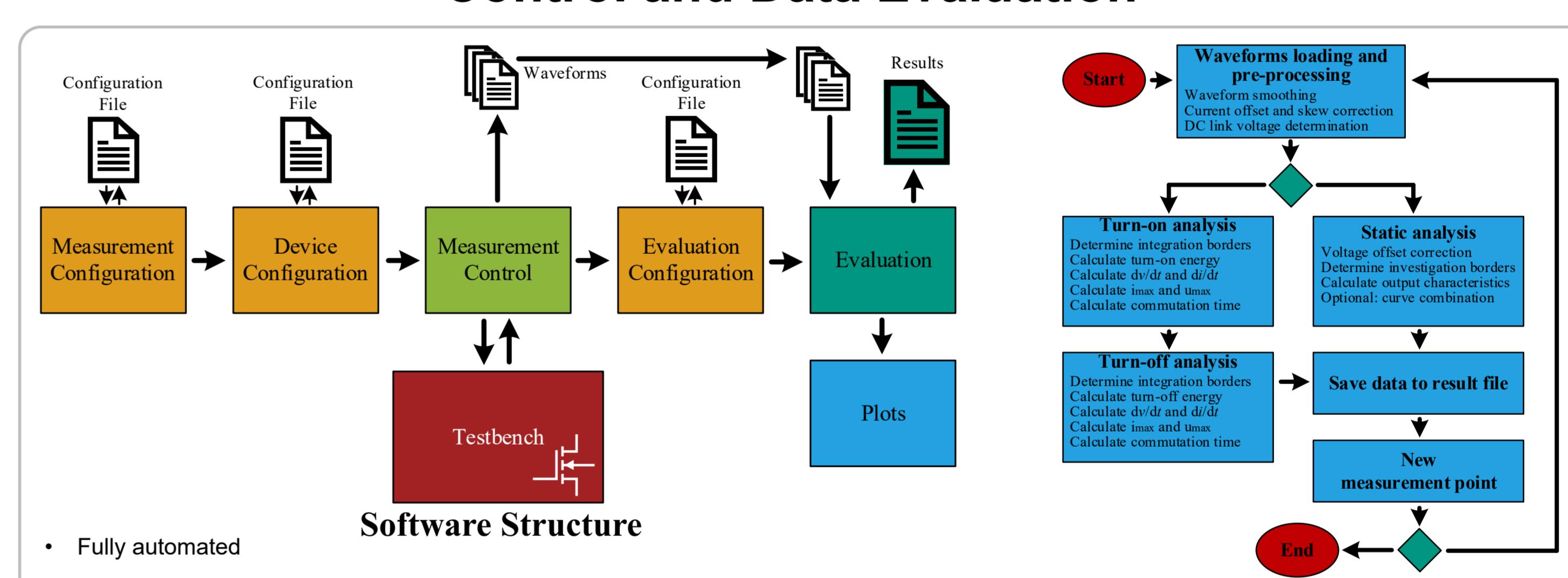
Dynamic Behavior



Static Behavior

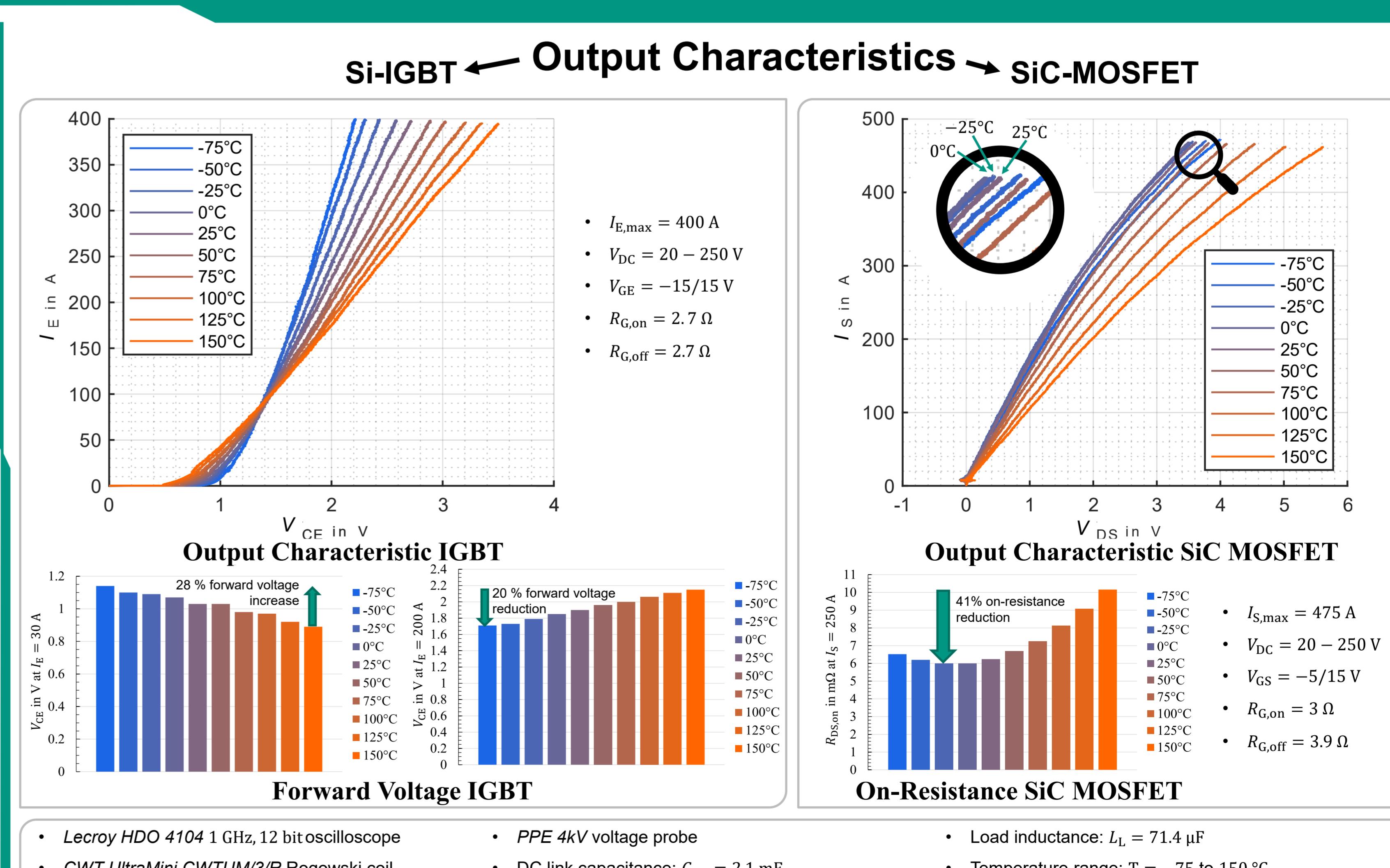
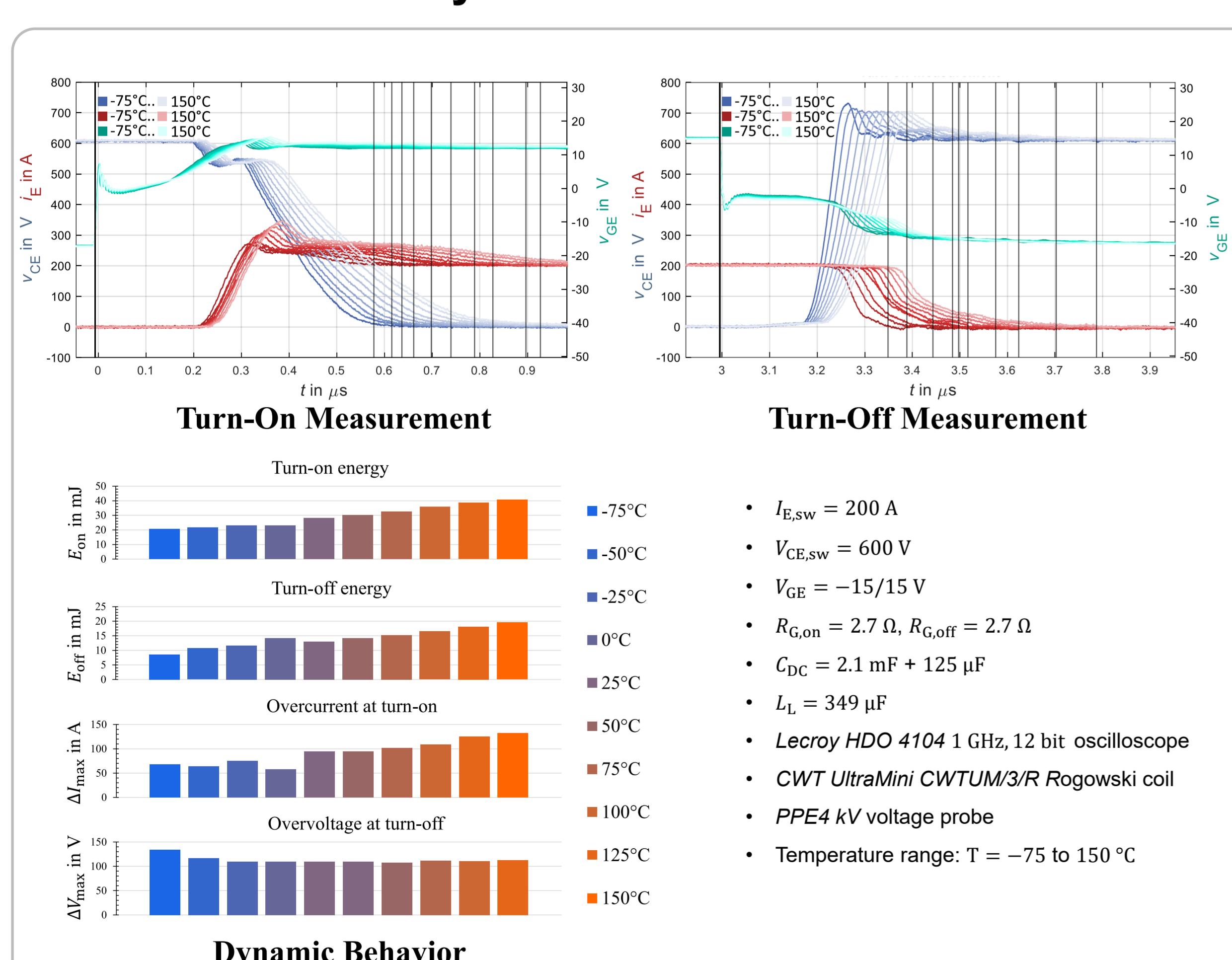


Control and Data Evaluation



Results

Dynamic Behavior



Summary

- Easy-to-use, flexible, wide temperature range test bench for static and dynamic characterization of power semiconductors
- Operation proofed over the temperature range from -75 to 150°C
- Static characterization without additional curve tracer
- Results promise more efficient converters when operated at lower temperatures

Future work

- Test bench adaption to GaN semiconductors
- Breakdown voltage measurements
- Further semiconductor measurements over a wide temperature range

